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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

CONFIRMATION NO. 3236

Applicant : Takayuki TOSHIMA, et al.
Serial No. : 10/052,534 Art Unit : 1746
Filed : January 23, 2002 Examiner : Michail KORNAKOV
For : Substrate Processing Apparatus and Substrate Processing Method

RESPONSE TO RESTRICTION REQUIREMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir :

A response to the Office Action mailed July 2, 2004 is due by August 2, 2004. The Action required restriction between

Group I of claims 1-19, drawn to a substrate processing apparatus, and

Group II of claims 20-34, drawn to a substrate processing method.

Applicants hereby elect Group I of claims 1-19, drawn to a substrate processing apparatus, for prosecution in this application.

Applicants reserve the right to file divisional application(s) for the non-elected claims in due course. In addition, Applicants advise that no change in the inventorship of the application is needed.

Applicants submit that this application now is in condition for examination on the merits and early action in that regard is solicited.

Respectfully submitted,

SMITH, GAMBRELL & RUSSELL, LLP

Brett L. Nelson, Reg. 48,119
for Michael A. Makuch, Reg. 32,263
1850 M Street, NW - Suite 800
Washington, DC 20036
Tel : 202/263-4300 - Fax : 202/263-4329

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